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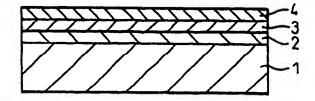
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- (54) Negative resist composition, process for forming resist patterns, and process for manufacturing electronic device
- (57) A negative resist composition is provided which comprises at least a constituent component which has a vinyl ether structure protected with an acetal in a molecule thereof. In the formation of negative resist patterns, an aqueous basic solution can be used without swelling.

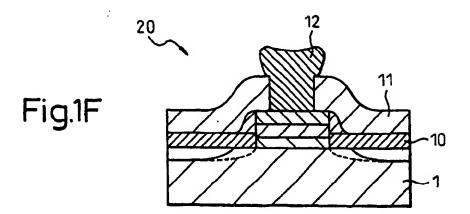
A process is also provided for forming a resist pattern, which comprises the steps of: applying a negative resist composition comprising at least a constituent component which has a vinyl ether structure protected with an acetal in a molecule thereof, on a to-be-treated

substrate; selectively exposing the formed resist film to imaging radiation capable of provoking decomposition of a photo acid generator of the resist composition, and developing the exposed resist film with an aqueous basic solution.

A process is also provided for manufacturing an electronic device, which comprises the step of selectively removing an underlying to-be-treated substrate using a resist pattern, formed from the above-mentioned process, as a masking means to form a predetermined functional element layer.

Fig.1A







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Application Number EP 01 30 7380

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ANNEX TO THE EUROPEAN SEARCH REPORT ON EUROPEAN PATENT APPLICATION NO.

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